

# SiO<sub>x</sub> as a model medium with large-scale potential fluctuations

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A model of large-scale potential fluctuations resulting from a local composition inhomogeneity is constructed from data on SiO<sub>x</sub> found by photoelectron spectroscopy. Electron-transport experiments confirm the predictions of the three-dimensional theory of percolation in a large-scale potential relief.

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Shklovskii and Éfros<sup>1,2</sup> have proposed a model for large-scale potential fluctuations in a compensated semiconductor in which the fluctuations result from an inhomogeneous distribution of donors and acceptors. Gadzhiev *et al.*<sup>3</sup> have shown that this picture is valid in neutron-bombarded *n*-type germanium. The local gap width remains constant in this model. A fundamentally new possibility is raised by the syn-

thesis of heterogeneous materials in which fluctuations of the local gap width  $E_g(Z)$  result from a composition inhomogeneity.

In this letter we will use experimental data to construct a potential-fluctuation model for  $\text{SiO}_x$ , and we will report an experimental test of the predictions of the three-dimensional theory of percolation in strong electric fields.<sup>4</sup>

The amorphous  $\text{SiO}_x$  films ( $x = 1.8, 1.6, 1.4, 1.2, 0.6$ ) were synthesized from the gas phase in a reaction of  $\text{SiH}_4$  and  $\text{N}_2\text{O}$  at  $T = 640^\circ\text{C}$ . The film composition was varied by varying the ratio  $\text{SiH}_4/\text{N}_2\text{O}$ . Figure 1 shows photoelectron spectra of the  $2S$  levels of silicon in  $\text{SiO}_x$  samples of various compositions (the excitation energy was  $E = 1586$  eV). The experimental spectra may be described as superpositions of peaks corresponding to the binding energies of the  $2S$  electrons in  $\text{SiO}_2$  and Si and a broad peak whose position is apparently determined by the degree of oxidation of the silicon in the matrix film, which we denote as  $\text{SiO}_y$ . These  $\text{SiO}_x$  films are thus heterogeneous, consisting of a mixture of Si,  $\text{SiO}_2$ , and  $\text{SiO}_y$ . The accuracy of the present experiments was such that we could not obtain more-detailed information on the composition.

The photoelectron spectra of the  $\text{SiO}_x$  valence band indicate that in the films containing a relatively large amount of silicon ( $x = 0.6, 1.4$ ) the top of the valence band lies  $5 \pm 1$  eV below the electron level in a vacuum. This result correlates well with the threshold ( $E = 5.2 \pm 0.1$  eV) for photoemission of electrons from amorphous silicon into vacuum.<sup>5</sup> As  $x$  is reduced, the top of the valence band descends monotonically from the vacuum level, to  $9 \pm 1$  eV in  $\text{SiO}_2$ . The latter result agrees with the threshold for electron photoemission from  $\text{SiO}_2$  into vacuum.<sup>6</sup> The shift of the top of the valence band from the vacuum level is accompanied by an increase in the optical width of the  $\text{SiO}_x$  energy gap, from 2 to 4 eV.

We can use these results to reconstruct the energy-band scheme of  $\text{SiO}_x$ . According to Fig. 2,  $\text{SiO}_x$  consists of clusters of Si and  $\text{SiO}_2$  which are "floating" in a

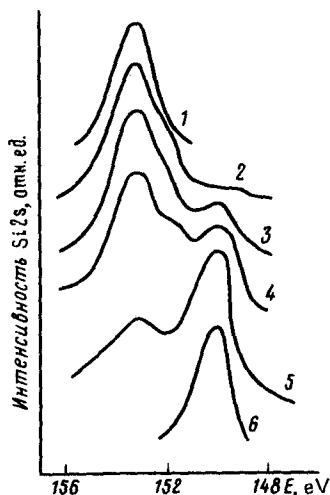


FIG. 1. Photoelectron spectra of the  $2S$  levels of Si in  $\text{SiO}_x$  for various values of  $x$ . 1— $\text{SiO}_2$ ; 2— $\text{SiO}_{1.8}$ ; 3— $\text{SiO}_{1.6}$ ; 4— $\text{SiO}_{1.4}$ ; 5— $\text{SiO}_{1.2}$ ; 6—Si. The energy is reckoned from the Fermi level of the spectrometer.

medium  $\text{SiO}_y$  of intermediate composition. The characteristic dimensions of the inhomogeneities in the  $\text{SiO}_x$  are  $10^{-6}$  cm, according to electron microscopy. A fundamental distinction between the scheme in Fig. 2 and the band-bending model<sup>2</sup> is that the internal fields tend to promote the recombination of nonequilibrium electron-hole pairs. The percolation energies for the electrons and the holes ( $E_n$  and  $E_p$ , respectively) are generally not equal in absolute value, in contrast with the band-bending model, because the potentials corresponding to the band edges  $E_c$  and  $E_v$  are not mirror images of each other.

The theory of percolation in a potential relief with large-scale potential fluctuations in strong fields predicts<sup>4</sup>

$$j = j_0 \exp \left[ - \frac{E_n - (Cea F V_0^\gamma)^{\frac{1}{1+\gamma}}}{kT} \right]. \quad (1)$$

Here  $C=0.25$  is a constant (Shklovskii<sup>4</sup> makes no claim that his theory yields an accurate value for this constant),  $\gamma=0.9$  is the critical index,  $a$  is the spatial dimension of the fluctuation, and  $V_0$  is the amplitude of the fluctuation. If  $\gamma$  is replaced by unity, expression (1) becomes the Poole-Frenkel' law. Study of the conductivity of  $\text{SiO}_x$  as a function of the field and the temperature indicates that expression (1) approximates the experimental data satisfactorily for  $x=1.4, 1.6,$  and  $1.8$ . At higher silicon contents (lower  $x$ ) the dielectric constant of  $\text{SiO}_x$  increases, and the slope of

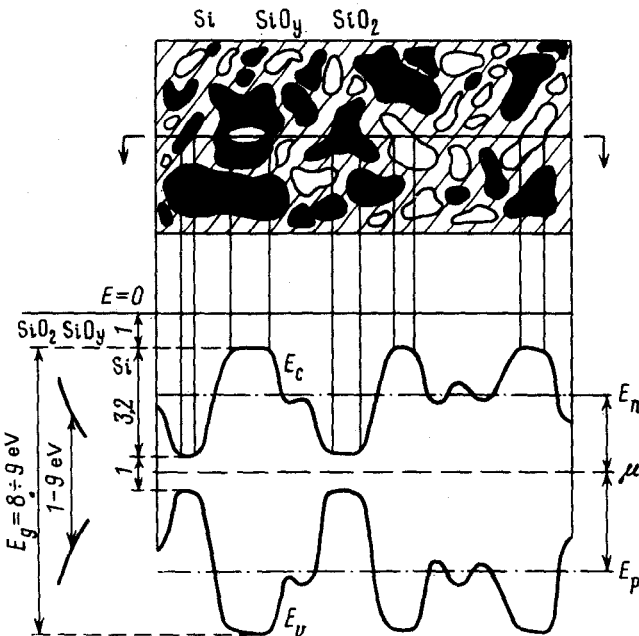


FIG. 2. (Top) Structure of  $\text{SiO}_x$ , (bottom) energy diagram of  $\text{SiO}_x$ .  $E_n, E_p$ —Percolation levels for electrons and holes; dashed line in the energy gap—Fermi level.

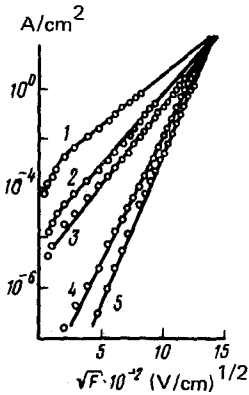


FIG. 3. I-V characteristics of  $\text{SiO}_{1.4}$  at various temperatures. 1— $T=470$  K; 2— $390$  K; 3— $290$  K; 4— $190$  K; 5— $80$  K.

the I-V characteristics, plotted as  $\log j - \sqrt{F}$ , increases. The usual interpretations of the the  $\text{SiO}_x$  conductivity in terms of the Frenkel' effect<sup>7</sup> or a contact-limited Schottky effect contradict the experimental data, since both interpretations predict a decrease in the slope of the I-V characteristic with increasing dielectric constant:  $d \log j / d \sqrt{F} \sim \epsilon^{-1/2}$ . The  $\text{SiO}_x$  percolation energy found from the experimental data ranges from 0.4 to 1 eV, depending on the composition. Figure 3 shows the experimental I-V characteristics. The percolation energy for this sample is  $E_{\text{perc}} = 0.4 \pm 0.1$  eV, and we find the product  $aV_0 = 6 \times 10^{-7}$  eV · cm. With  $V_0 = 1$  eV,  $a$  is  $6 \times 10^{-7}$  cm. We should therefore assume that the  $\text{SiO}_x$  conductivity results from a percolation of electrons through the potential relief formed by the Si and  $\text{SiO}_y$ . The fraction of the volume occupied by these phases (which can be estimated from Fig. 1) is  $0.25 \pm 0.1$ , higher than the critical fraction of 0.15 required for the formation of an infinite cluster in the overlapping-sphere model.<sup>8</sup> Percolation theory in strong fields has been derived for a homogeneous medium with  $E(Z) = \text{const}$ . For a correct description of percolation in inhomogeneous media, we need a theory which incorporates the redistribution of the electric field caused by fluctuations of the dielectric constant,  $E(Z)$ .

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